

Resource Summary Report

Generated by [SPARC SAWG](#) on Aug 9, 2026

Rigaku: TXRF-V310

RRID:SCR_020484

Type: Tool

Proper Citation

Rigaku: TXRF-V310 (RRID:SCR_020484)

Resource Information

URL: <https://www.rigaku.com/products/semi/txrf-v310>

Proper Citation: Rigaku: TXRF-V310 (RRID:SCR_020484)

Description: Wafer surface contamination metrology by VPD TXRF with measurement of ultra trace elemental surface contamination.

Resource Type: instrument resource

Keywords: Rigaku, Semiconductor Metrology, Instrument Equipment, USEDit,

Availability: Commercially available

Resource Name: Rigaku: TXRF-V310

Resource ID: SCR_020484

Alternate IDs: Model_Number_TXRF-V310

Record Creation Time: 20220129T080350+0000

Record Last Update: 20260808T190154+0000

Ratings and Alerts

No rating or validation information has been found for Rigaku: TXRF-V310.

No alerts have been found for Rigaku: TXRF-V310.

Data and Source Information

Source: [SciCrunch Registry](#)

Usage and Citation Metrics

We have not found any literature mentions for this resource.